

06/12/01
U.S. PTO

Docket No. 005643/CALB/L/B

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application
Assistant Commissioner for Patents
Washington, D.C. 20231

Re: Inventor(s): Sean Michael Seutter, Seshadri Ganguli, Mei Chang, Michael X. Yang, Ming Xi
Title: Low-Resistivity Tungsten from High-Pressure Chemical Vapor Deposition
Using Metal-Organic Precursors

JC872 U.S. PTO
09/880465
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Transmitted herewith is the patent application identified above, including:

- Specification, claims and abstract, totaling **25** pages.
 Drawings totaling **6** pages, Formal Informal.
 Executed Declaration and Power of Attorney.
 Assignment of the invention to **Applied Materials, Inc.**
 Assignment Recordation Cover Sheet

Information Disclosure Statement, PTO Form 1449 and () References

FEE CALCULATION					
Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	- 24	- 20 =	- 4	X \$18	\$ 72
Independent Claims	- 3	- 3 =	- 0	X \$80	\$ 0
Basic Filing Fee				\$710	\$710
TOTAL FEES					\$782

- The Commissioner is hereby authorized to charge **\$782** to Deposit Account No. 50-1074
 The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 50-1074. A duplicate copy of this transmittal is enclosed.
 Please address all future correspondence to:

PATENT COUNSEL
APPLIED MATERIALS, INC.
Legal Affairs Department
P.O.BOX 450A
Santa Clara, CA. 95052

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to Box Patent Application, Assistant Commissioner for Patents, Washington, D.C. 20231

Express Mail Receipt No E266150459C05

Date of Deposit 6/12/01

Signature Robert W. Mulcahy

Respectfully submitted,

Robert W. Mulcahy
Registration No. 25,436